## S/N Unknown

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant:

Gurtej Singh Sandhu et al.

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METHOD FOR FORMING A METALLIZATION LAYER

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## SUPPLEMENTAL PRELIMINARY AMENDMENT

Commissioner for Patents Washington, D.C. 20231

When the above-identified patent application is taken up for consideration, please amend the application as follows:

## IN THE CLAIMS

Please cancel claim 1 without prejudice, and add new claims 21-54 as follows.

- 21.

Please cancel claim 1 without prejudice, and add new claims 21-54 as follows.

(New) An integrated circuit, comprising:

a substrate;

a first layer of material formed on the substrate, the first layer having contact was extending through to the substrate;

- a second layer formed on the first layer, the second layer lining the contact vias; and a metallization layer on the second layer.
- (New) The integrated circuity of claim 21, wherein the metallization layer comprises non-22. alloy copper.
- (New) The integrated circuitry of claim 21, wherein the metallization layer fills the 23. contact vias.
- (New) The integrated circuitry of claim 21, wherein the first layer has a first surface 24. potential and the second layer has a second surface potential, and wherein the first surface potential is lower than the second surface potential.

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